

## HVMAPS for Mu3e and beyond





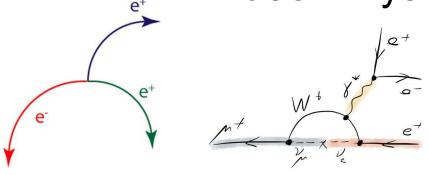
Heiko Augustinfor the Mu3e Collaboration Physikalisches Institut Heidelberg

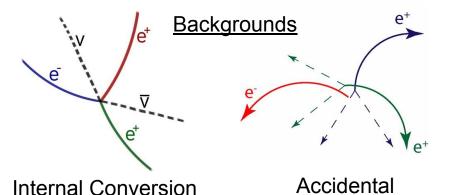
Vienna Conference on Instrumentation 2025

19.02.2025



## Mu3e: Physics Motivation

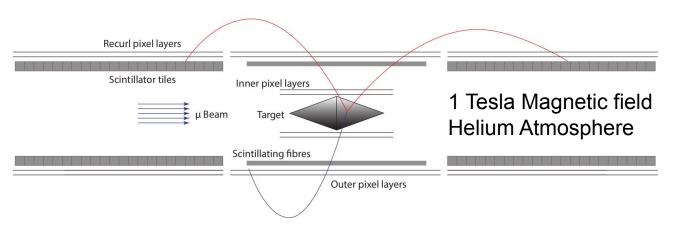


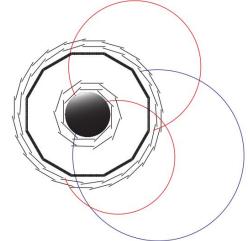


- Search for the cLFV decay μ<sup>+</sup>→ e<sup>+</sup>e<sup>-</sup>e<sup>+</sup> (vSM: BR < 10<sup>-54</sup>)
- Current limit (SINDRUM) BR < 10<sup>-12</sup> @ 90% CL
- Sensitivity goal (Phase1):
   1 in 10<sup>15</sup> decays
- Up to 10<sup>8</sup> decays per second
- Suppress background below sensitivity level

More on Mu3e! Elizaveta Nazarova →Tuesday 18.2. Sandro Bravar →Thursday 20.2.

#### The Mu3e Detector





- 10<sup>8</sup> decays per second
- $p_{max} = m_{\mu}/2 = 53 \text{ MeV}$ 
  - Multiple CoulombScattering
  - → Triplet Track Fit [arXiv:1606.04990v2] [arXiv:2406.05240v2]

- Good vertex and time resolution (100 μm & 500 ps)
- Excellent momentum resolution (0.5 MeV)
- Continuous Beam! No trigger!
  - → Online reconstruction and selection

Helium Gas Cooling [arXiv:2301.13813], [arXiv:2307.14803]

# Market

#### The Mu3e Detector

#### Pixel detector requirements:

Pixel Size	Time Resolution	Material Budget	Efficiency
80 x 80 μm <sup>2</sup>	< 20 ns	0.1% X <sub>0</sub> /layer	> 99 %

#### Mu3e TDR [arXiv:2009.11690v3]

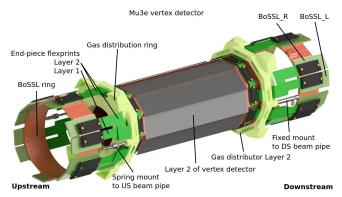
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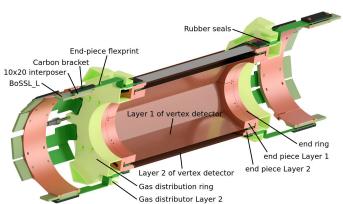
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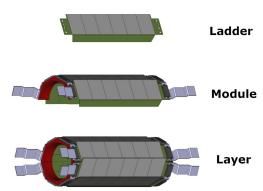
Helium Gas Cooling [arXiv:2301.13813], [arXiv:2307.14803]

## Ma

## Tracking System - Vertex Detector Layer 0+1



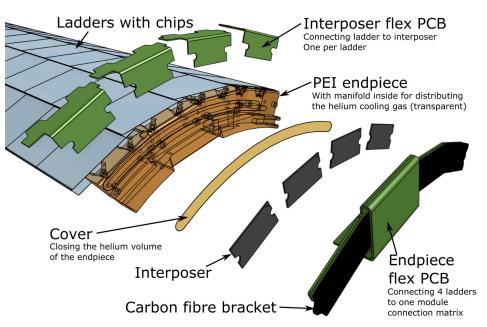


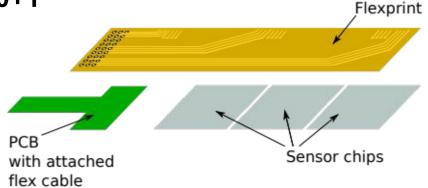


Chips glued and bonded High Density Interconnects (HDIs)

- 6 for layer 0 and 1
- 17/18 for layer 2 and 3
- 50 µm thin
- Connection via interposers (pressed against RO flexes)

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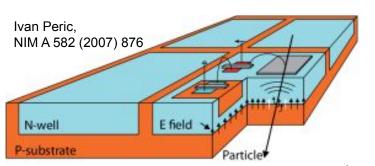




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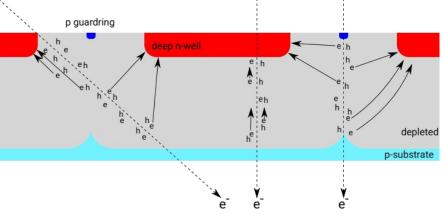
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## High Voltage - Monolithic Active Pixel Sensors



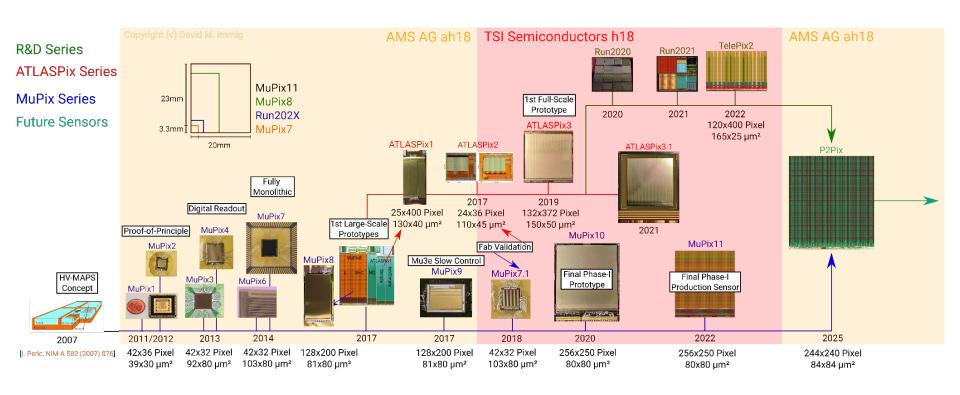
- Commercial HV-CMOS processes: TSI 180nm (h18)
- Deep N-well diode (large fill factor)
- Low Ohmic substrates (10-400  $\Omega$ cm)
- High voltages up to 100V
- Charge collection via drift

- In-pixel electronics
- Monolithic design: Detection and Readout combined in one chip
- Chips are thinned to 50 µm





## MuPix/HV-MAPS R&D process

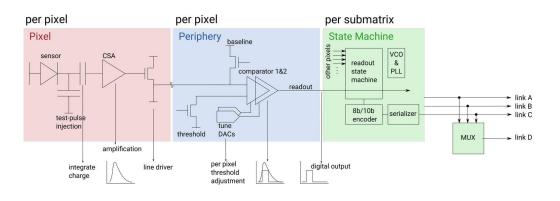


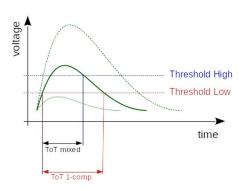


## The MuPix Sensor



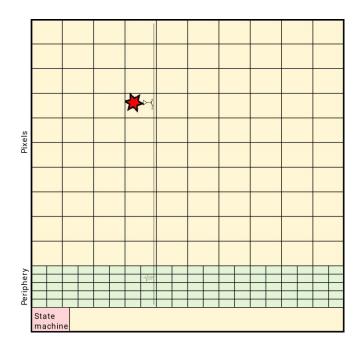






- Clear separation of analog and digital electronics
- 2 comparator design
- Tuning/Trimming and masking available
- Priority encoder / column-drain readout
- Chip sub-divided into 3 matrices → 1 Data link each + 1 multiplexed link

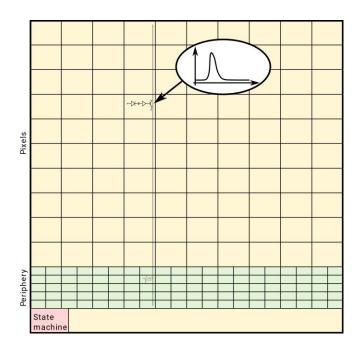




Courtesy: Frank Meier

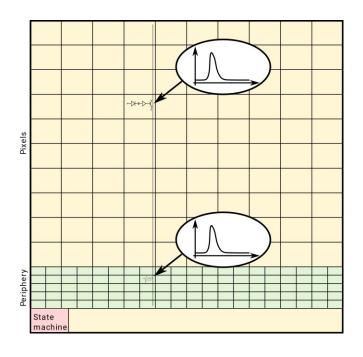
- Deposited charge amplified by in-pixel amplifier
- Source follower drives the signal to the periphery
- Digitisation in periphery
- Timestamp sampling
- Readout statemachine manages column-drain readout
- Data is send out via a 1.25 Gbit/s differential link





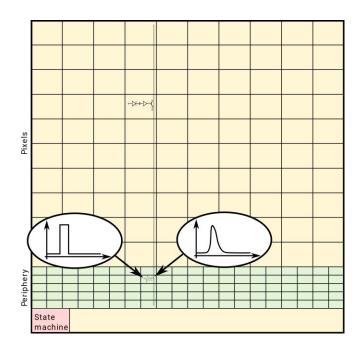
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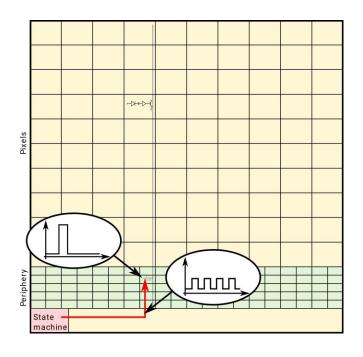
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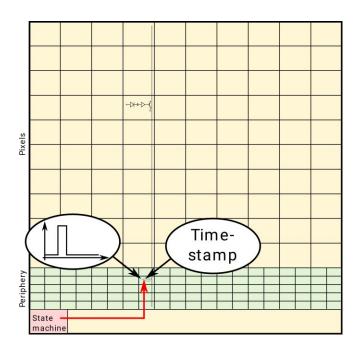
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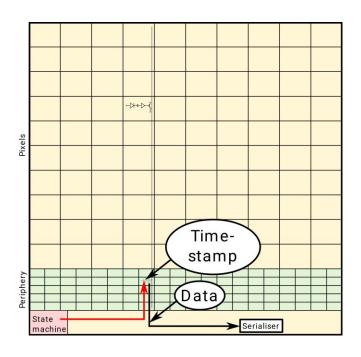
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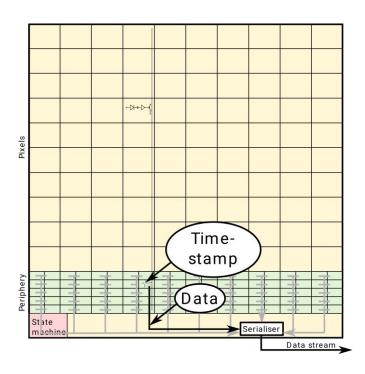
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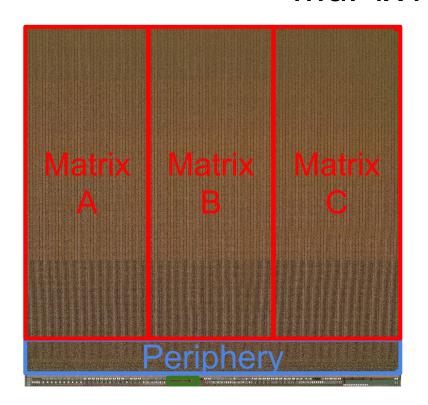




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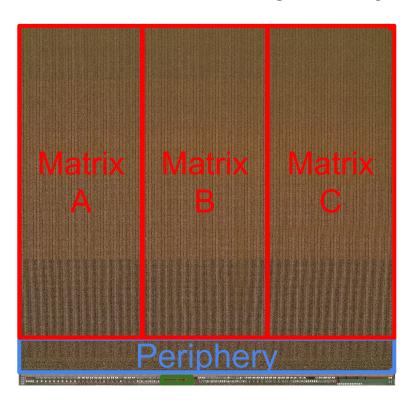
#### MuPix10 & MuPix11



Pixel size [µm²]	80 x 80				
Sensor size [mm²]	20.66 x 23.18				
Active size [mm²]	20.48 x 20.0				
Pixel matrix	256 x 250				
Thickness [µm]	50, 70				
Substrate [ $\Omega$ cm]	80, 370				
Data links	3+1				
Data speed [Gbit/s]	1.25				
Time-of-arrival [bits]	11				
ToT [bits]	5				
TS binning [ns]	8 (option for 1.6)				

# Market

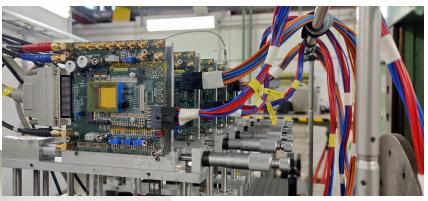
#### From MuPix10 to MuPix11



- Removal of R&D features
  - → More pads for powering
- Improvement of powering grid
  - → Less on-chip voltage drop
- Buffering of data lines
  - → Full speed readout30 MHits/s per sub-matrix
- Re-synthesis of State machine
  - → Fast configuration interface available
- Re-done pixel point-to-point connection
  - → Reduced delays and parasitic couplings



#### **Sensor Characterisation**



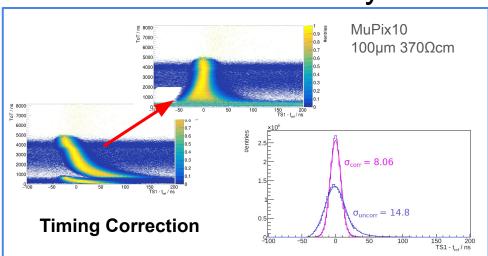


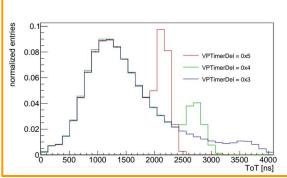


- Lab commissioning
- Lab optimisation: Radioactive sources: <sup>55</sup>Fe, <sup>90</sup>Sr Time coincidence
- Testbeam Campaigns:
   DESYII (Hamburg, GER)
   MAMI (Mainz, GER)
   PSI piM1 (Villigen, CH)
- MuPix-Telescope
- Mimosa/Alpide-Telescopes

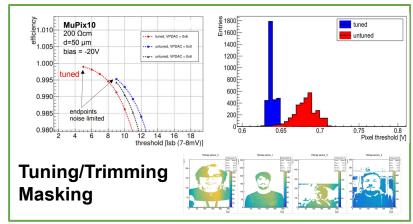


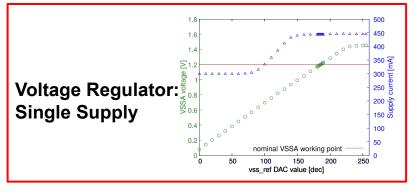
#### Summary - Results MuPix10





Hit readout delay: Hit Chronology

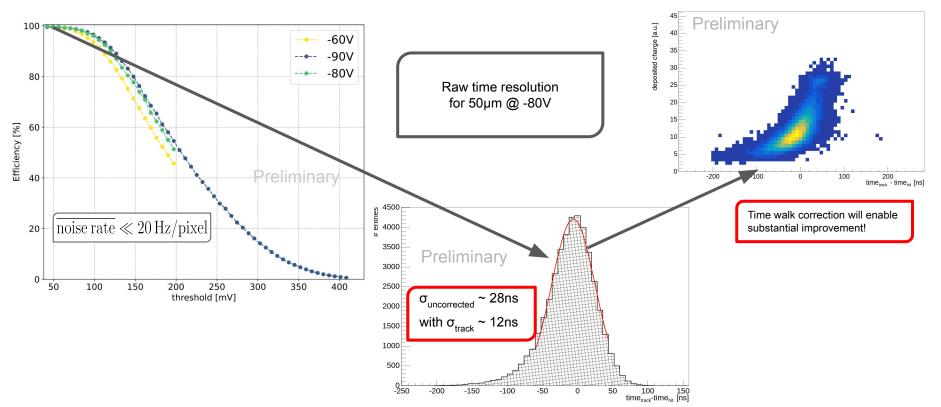




[arXiv:2012.05868] & 10.7566/JPSCP.42.011020

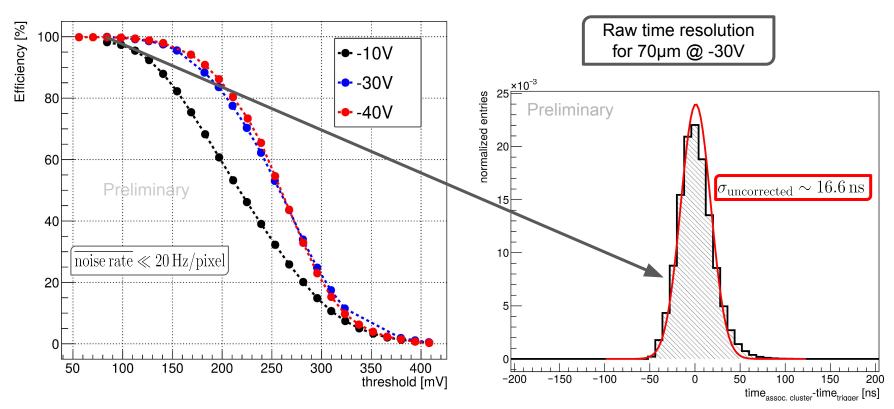


#### MuPix11 - 50 $\mu$ m - 80 $\Omega$ cm (Vertex detector)



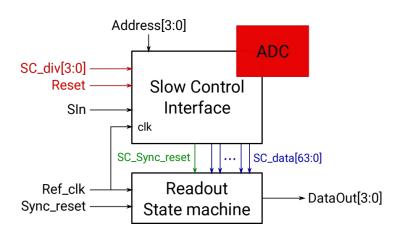


### MuPix11 - 70 $\mu$ m - 370 $\Omega$ cm (Outerlayers)

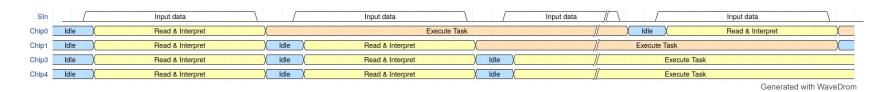




## MuPix Fast Configuration Interface

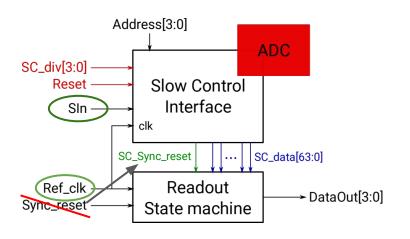


- Chips of a ladder share a bus of clock, synchronous reset and configuration input
- Custom configuration protocol
- Commands interleavable
- ~400ms configuration time for 9 chip ladder
   ⇒ Configuring the ladder is not a bottleneck
- On-going development for future use

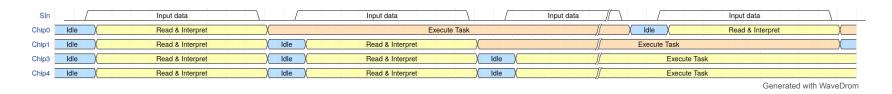




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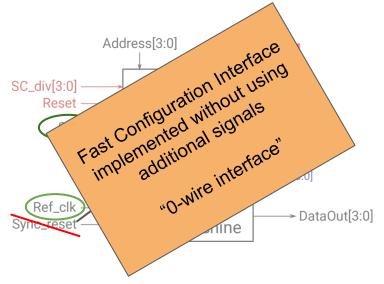


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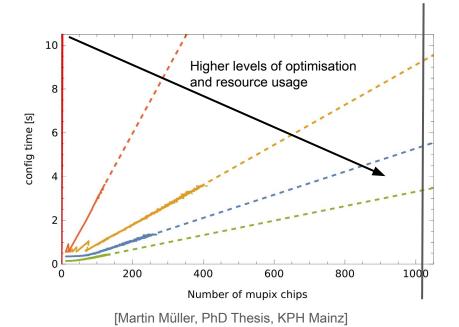


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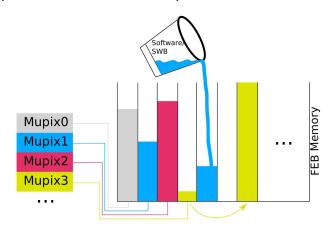
SIn		Input data		Input data		Input data		Input data
Chip0	Idle	Read & Interpret	X	Execute Task			Idle	Read & Interpret
Chip1	Idle	Read & Interpret	Idle	Read & Interpret			Execute Ta	sk
Chip3	Idle	Read & Interpret	Idle	Read & Interpret	Idle	X	E	xecute Task
Chip4	Idle	Read & Interpret	Idle	Read & Interpret	Idle	X	E	xecute Task
								Generated with WaveDrom



### Configuring the Mu3e Central Pixel detector

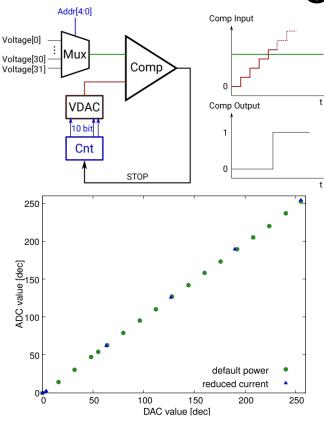


- The bottleneck is to get the data to the chip
- Firmware optimisation towards data preparation
- Detector currently configurable < 4s (emulated detector)



## On-chip ADC





- ADC programmable through Mu3e configuration interface
- Allows measurement of on-chip voltages
- Data send out via 1.25 Gbit/s data links
- ADC shows a good linearity

## Me

45.0°C

\_ 38

36

\_ 34

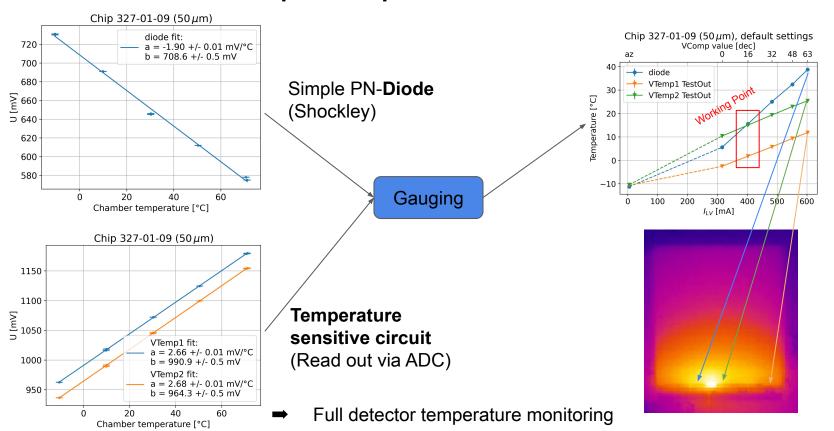
32

30

24

22,1°C

### On-Chip Temperature Measurement





45.0°C

\_ 38

36

\_ 34

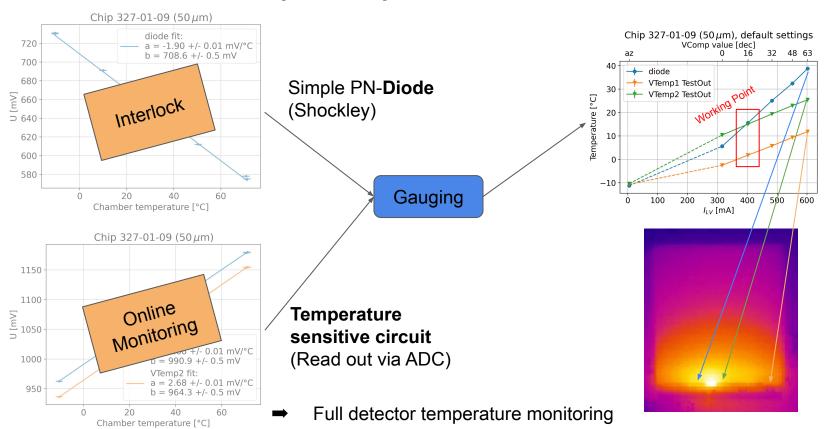
32

30

24

22,1°C

### On-Chip Temperature Measurement





### **Vertex Detector Status**

Photos from Thomas



## Outlook - Future of HVMAPS

TelePix2, P2Pix, explore new foundries, Conditions Mu3e Phase



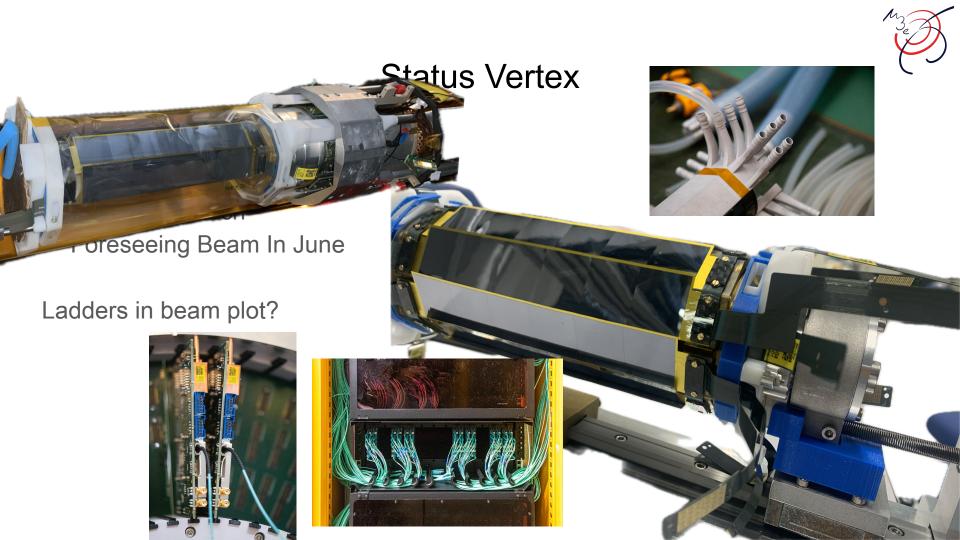
#### MuPix11 a sensor of

Stuff from luigis review poster

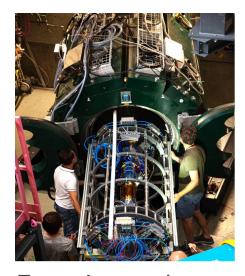
Mu3e ~ 150 Wafers



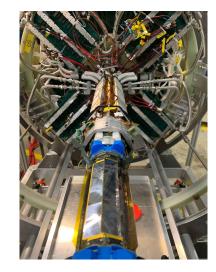








ion into the Mu3e Magnet



First Installation of the Mu3e Vertex Detector (December 2024)



#### Re-Roadmap

Moeller, P2, Panda, MuSR [MKref], Telescope-Maintenance

- $\rightarrow$  P2Pix
- $\rightarrow \text{MightyPix}$
- → Mu3e Phase 2

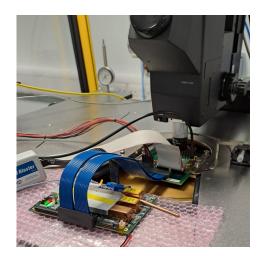
Types

Xfab



#### Summary & Outlook

- Successful transition from MuPix10 to MuPix11
  - Everything functional, expected to fulfill Mu3e requirements
- QC procedures have been developed and implemented
  - First successful test of needle card for large volume testing
- Production of Vertex ladders started
  - First in-beam test still this week
  - Full vertex detector expected in Spring
- First ladders of outer pixel layers expected in Spring
- Start with detector commissioning next year

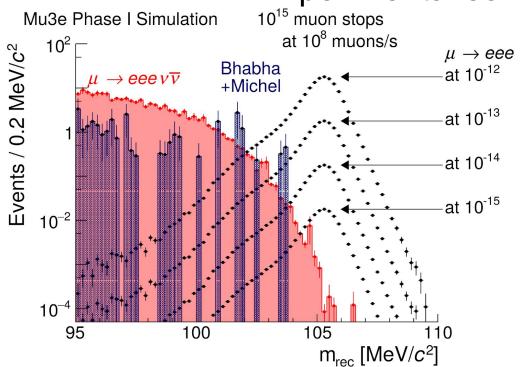




## Backup



#### Experimental sensitivity



Invariant mass of signal decay, radiative decay and accidental background (Bhabha+Michel)

Momentum resolution crucial for detecting the peak at muon mass...

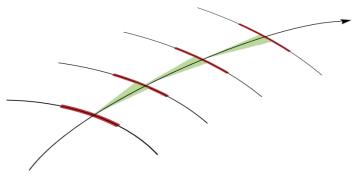
## Material budget is key factor!

1 MeV resolution with 0.1% \* X/X<sub>0</sub> per layer

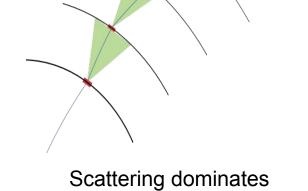
Mu3e TDR at Nucl.Instrum.Meth.A 1014, 165679







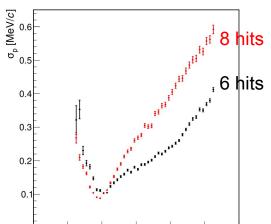




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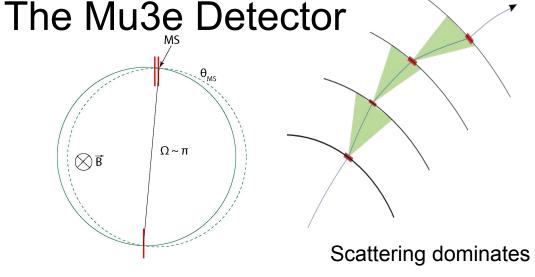




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 $p_{mc} [MeV/c]$ 

Triplet Fit [arXiv:1606.04990v2]

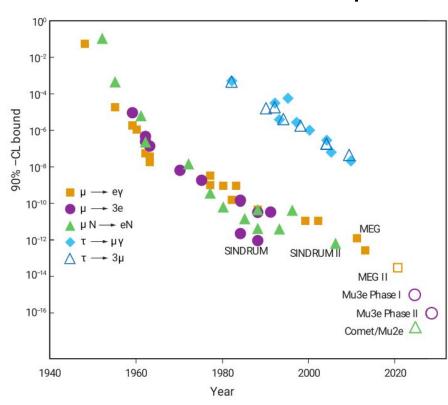


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#### cLFV - Landscape

#### updated?

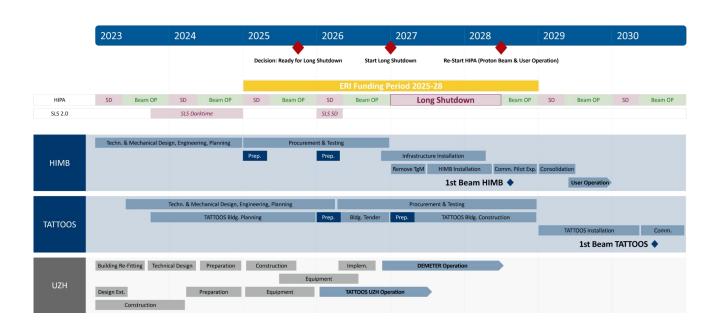




#### PSI - Beamline Upgrades

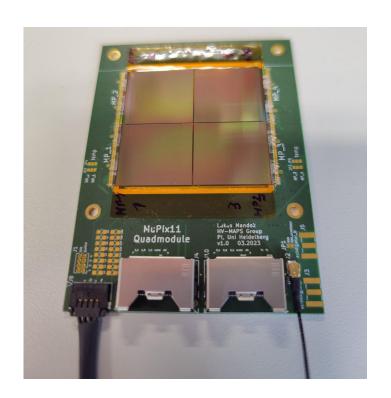
#### updated

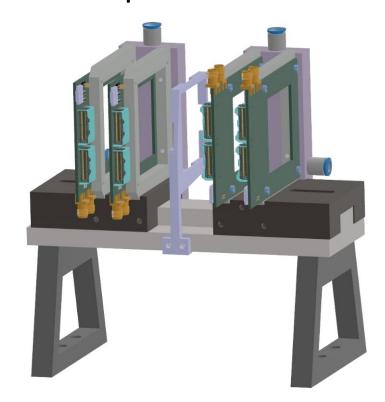
#### **IMPACT** Timeline





### Quad - Module Telescope

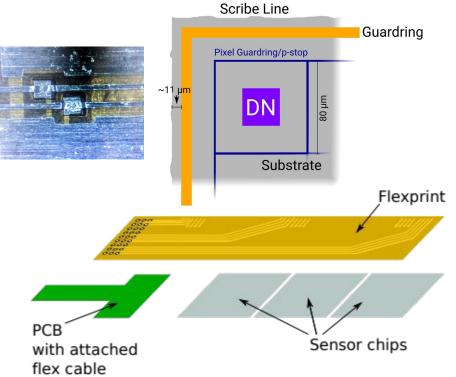




#### A MuPix Module

My

- Chips glued and SpTAB-bonded to flexprint
- No additional components!
- 1.15‰ X<sub>0</sub> per layer
- Minimize dead space between the chips
- Only 11 µm dead silicon outside the guardring
- Power consumption limited to 400 mW/cm² (Sensors+Flex)

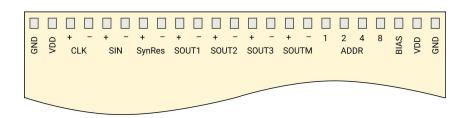




## The Flexprint Environment

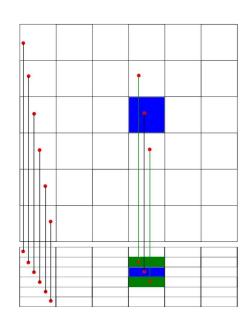
- 2 layer aluminum polyimide flexprint (LTU)
- Provides: Power & HV (parallel) Differential Signal I/O
- Only 1 supply voltage, but no LDO-regulators!
- Minimise I/O
- Flex design rules define PadOut

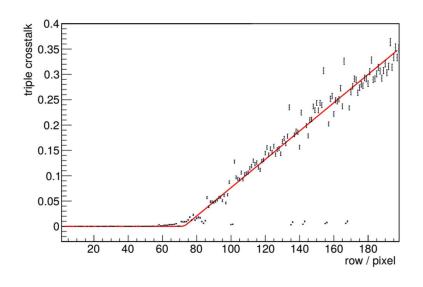






## Signal Line Crosstalk - MuPix8

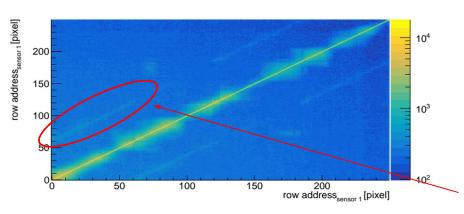




Triple Crosstalk: hit induced in both neighbouring lines



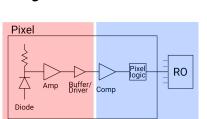
## Routing Optimisation - MuPix10



- Equalize but reduce crosstalk
   →miminise the length that two line are
   neighbouring
   (¼ of total length, 2cm)
  - ~12% triple crosstalk expected
- Make Crosstalk easily detectable

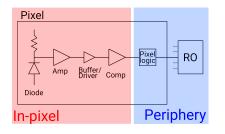
   → neighbouring signal lines are not
   neighbouring pixels
  - Crosstalk can be removed, possibly already during the data taking
- Even more improvement expected for MuPix11

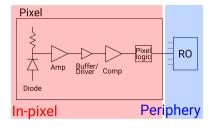
## Beyond MuPix11 - Roadmap -- Architectures

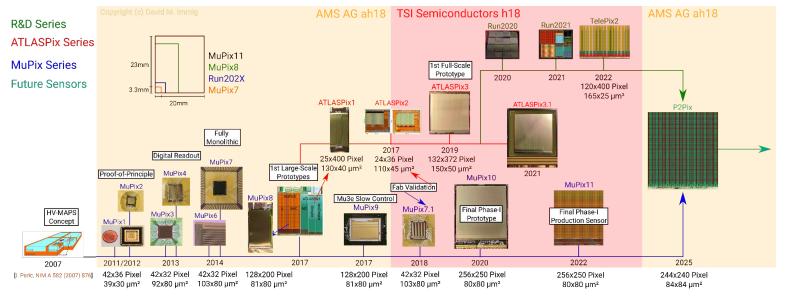


In-pixel

Periphery

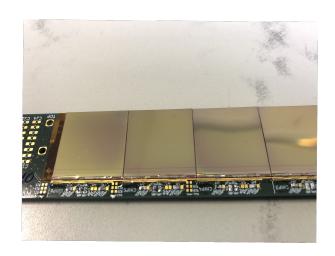






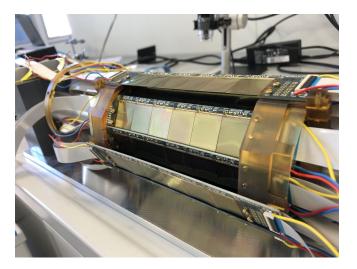


#### Proto Vertex Detector



- First proto-detector with 6 chips modules
  - Still PCB based!!!

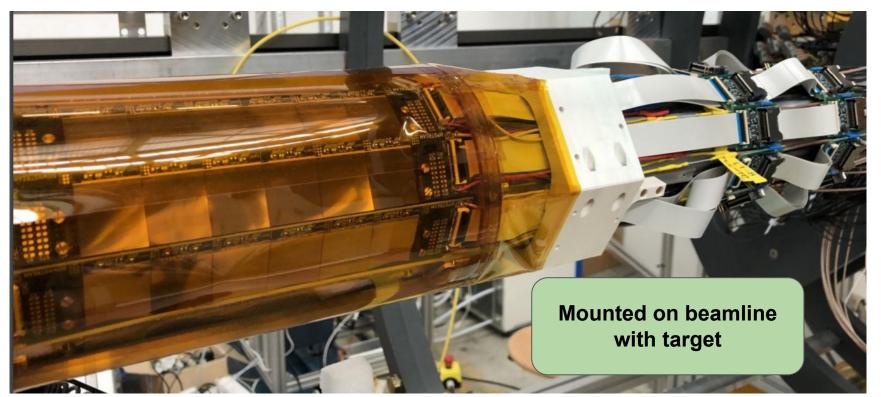
- Two layer vertex detector (MuPix10)
  - Gain operational experience
  - Test Mu3e readout chain





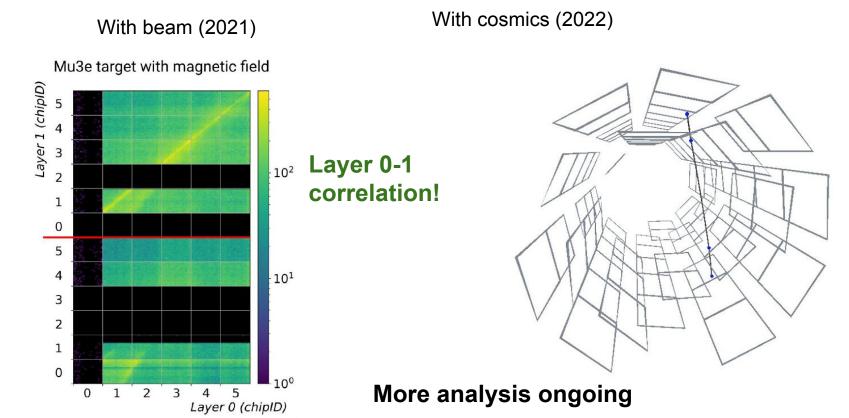
#### Operation in experimental conditions

DAQ and experimental concept



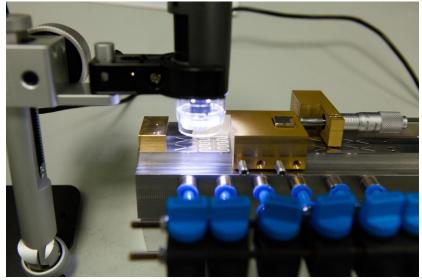


#### Operation in experimental conditions





Production of inner layers



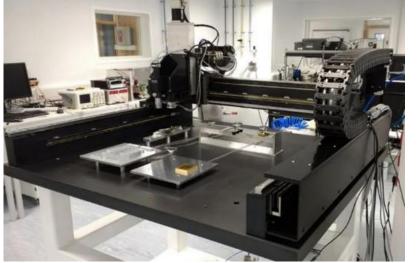
#### Heidelberg/PSI

Quick demo: <a href="https://youtu.be/0SYqHSbH3U4">https://youtu.be/0SYqHSbH3U4</a>





Production of outer layers



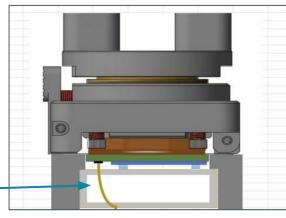


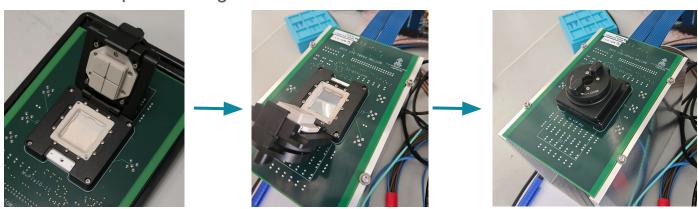
#### Oxford/Bristol/Liverpool



#### Quality Control (QC)

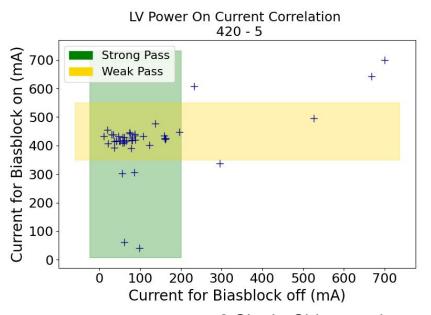
- Quality assurance is key before a large scale detector assembly
- Testing after assembly is too risky and costly, since dismantling is impossible
- Press down mechanism with contact needles for prior testing

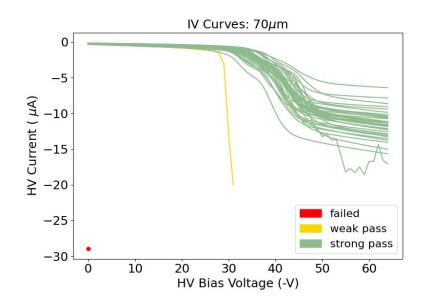






#### QC - Test procedures

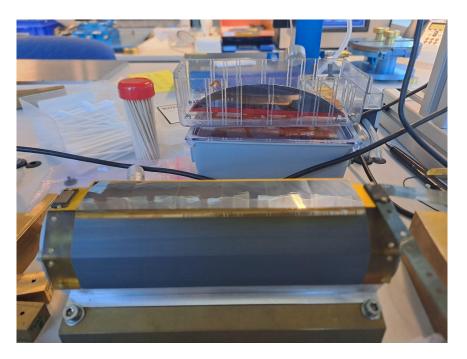




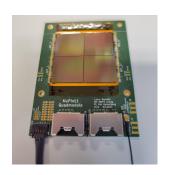
- 2 Single Chip test sites
- First needle card test station being setup in Oxford
- QC procedure still being refined, but almost final
- Grading scheme still adjusting (pre-production)



#### The Vertex Detector



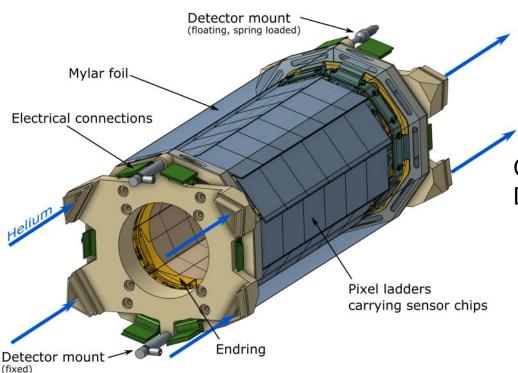
- First Vertex ladders have been produced
- Ladder QC under development in parallel to single chip QC
- Fully functional 50µm ladder in Hand
- Currently running beam time at PSI:
   First time in-beam commissioning of final ladder





# Mge

# Tracking System - Vertex Detector Layer 0+1



Chips glued and bonded High Density Interconnects (HDIs)

- 6 for layer 0 and 1
- 17/18 for layer 2 and 3
- 50 μm thin
- Connection via interposers (pressed against RO flexes)



#### In-House Wafer Handling

 Diced and thinned wafers delivered on tape

- Equipement:
  - Vacuum chuck
  - Pick-up tools (tweezer & suction pen)
  - A lot of patience & time
- Pending on use case thickness vary between 50μm to 100μm + 750μm

Mu3e ~ 150 Wafers

